								Tim	(9)	Note	
7. The EDDM current sensors follow (A) Faraday's law of induction (C) Coulomb's law	6. Hall effect transducers can be used to measure (A) Sound (B) (C) Pressure (D)	 Gauge factor of a strain gauge represents Accuracy Sensitivity 	4. Which of the following is a digital transducer? (A) Thermistor (B) (C) RTD	 Load cell is a transducer which measures Force Temperature 	Which one is an active transducer? (A) RTD (C) Strain gauge	The smallest change in input a transducer can sense (A) Precision (B) A (C) Sensitivity (D) R	PART – A (20 × 1 = 20 Marks) Answer ALL Questions	Time: Three Hours		EC1105 — SENSORS AND TRANSDUCERS (For the candidates admitted during the academic year 2013 — 2014 and 2014-2015)	B.Tech. DEGREE EXAMINATION, NOVEMBER 2018 Fourth/Fifth/Sixth Semester
B	asure (B) (D)	ÐB		(B)	98	(B)	XI=		within i ute. answer	AND T	ATIO Sixth S
Gauss's law Ampere's circuital law	Power Rotational angle	Dead zone Permituvity	LVDT	Strain	(D) LVDT	n sense (B) Accuracy (D) Resolution	20 Marks) estions	Max. Marks: 100	Part - A should be answered in OMR sheet within first 45 minutes and OMR sheet should be handed over to hall invigilator at the end of 45 th minute. Part - B and Part - C should be answered in answer booklet.	TRANSDUCERS 5 year 2013 - 2014 and 2014 -2015)	N, NOVEMBER 2018 emester

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The magneto resistive effect in ferromagnetic material is
 (A) Anisotropic
 (B) Geometrical
 (C) Isotropic
 (D) Linear

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20.	19.	90	17.	16.	15.	14	13.	12	H	10.	9.
The radiation wavelength of I (A) 6 to 10 nm (C) 10 nm to 20 nm	The surface acoustic devices are used to (A) Sense change in frequency due to gas (C) Sense gas with respect to time	The overall film sensor sensitivity depends on (A) Porosity (B) (C) Thickness of the material	An example of naturally occurring piezoelectric sensor is (A) Silicon dioxide (B) Lithium (C) Barium fitanate (D) Rochell	GM counter can measure (A) Alpha rays (C) Gamma rays	The resistance ratio change depends on (A) Illumination (C) Input voltage	The capacitors fringing effects are reduced by (A) Sensitivity factor (C) Permittivity (I)		The variation of inductance can be measured using (A) AC bridge circuits (B) R (C) RC circuit with DC excitation (D) L	To avoid eddy current loss, the core in LVDT is made of (A) Silica sheets (B) Single (C) Stacked stamped sheets (D) Withou	The coil dissipation factor D_c (A) $D_C = \frac{R_C}{\omega_L}$ (C) $D_C = \frac{z_C}{\omega_L}$	(C) Synchro
thographic galvario (B) 0 (D) 3	(B)	99	rring piezoelectric se (B) I (D) F	(B) / (D) /	(B)	99	e on both sides of the (B) I (D) C	in be measured using (B) R (ation (D) I	e core in LVDT is m (B) S (D) V	(B) _L	cal transformer used i (B) L (D) R
The radiation wavelength of lithographic galvario formung abformung –LIAC is (A) 6 to 10 nm (B) 0.1 to 2 nm (C) 10 nm to 20 nm (D) 3 nm to 5 nm	Sense gas due to change in frequency Sense gas absorption and deposition of material	Resistivity	ensor is Lithium sutphate Rochelle satt	Alpha and beta rays Alpha, beta and gamma rays	in radiation sensors. Materials Illumination and materials	Guard ring Varying distance between two plates	Equalization of steady pressure on both sides of the diaphragm to prevent it from bursting is (A) Leakage effect (B) Damping effect (C) Hysteresis effect (D) Oscillation effect	ag RC circuit with AC excitation LC circuit with AC excitation	made of Single sheet Without sheets	$D_C = \frac{R}{\omega_o}$ $D_C = \frac{R_C}{\omega_{CL}}$	type of electrical transformer used for measuring angular displacement. (B) LVDT (D) Resolver

PART – B $(5 \times 4 = 20 \text{ Marks})$ Answer ANY FIVE Questions

- What are the parameters required to choose a good transducer?
- 22. Classify active and passive transducers with suitable examples.
- 23. How can strain developed on a strain gauge be measured using a full-bridge configuration?
- 24. Explain the working principle of RVDT using necessary diagrams.
- 25. Write about the different modes of deformation in piezoelectric materials
- Explain the principle to measure temperature using fiber opticsensors.
- 27. Write a note on the oxygen level sensors.

PART - C (5 × 12 = 60 Marks) Answer ALL Questions

- 28. a. Explain the static and dynamic characteristics of transducers.
- (OR) Discuss in detail the classification of errors.
- 29. a. Derive the relation between the resistance and voltage due to the effect of magnetic field in anitsotropic magneto resistive sensors.
- ò Explain about the working of strain gauge and explain its various types. Derive the expression for the gauge factor.
- a. Describe the working of frequency modulating oscillator and DC circuit for dynamic capacitance variation.
- (OR)
- b. Explain the LVDT operation using necessary diagrams. Draw its hysteresis loop.
- a. Explain the operation of a photovoltaic cell with suitable diagram and draw the V-I characteristics.

- (OR) Write in detail about the electrochemical cell and explain how it works as a sensor.
- 32. a. Write the fabrication steps of thin and thick film technology and state their differences.

b. Enumerate on the "on-board" automobile sensors with suitable diagrams

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Page 4 of 4 12NF3-7/15EC226E										H 19	b. With near block diagram explain the home automation system and the various sensors used in it.	 ii. Using piezoelectric sensor measure acceleration. (4 Marks) 32. n. Write in detail the on-board automotive sensor. 	b.i. Write about piezoelectric sensor and its deformation modes. (8 Marks)	31. a. Explain how to measure the temperature and liquid level using fiber optics sensor with diagram.	•
	7. The complete failure in the normal operation of sensor is called (A) Wear out (B) Noise (C) Leakage current (D) Breakdown	 6. An element that senses a variation in form of energy is called (A) Electrode (C) Sensor 	 Microphone is a sensor which converts (A) Light energy (C) Mechanical energy 	4. is a kind of variable resistance transducer. (A) Resistive potentiometer (B) (LVD) transfe (C) Varactor (D) Capaci	3. The smallest change in input that a transducer can sense is known as (A) Sensitivity (B) Resolution (C) Precision (D) Accuracy	(C) Electrical energy to mechanical energy	An inverse transducer converts (A) Mechanical energy to electrical	1. The gauge factor is defined as $(A) \frac{(\Delta L/L)}{(\Delta R/R)}$ $(C) \frac{(\Delta R/R)}{(\Delta D/D)}$	PART – A (Answer	Time: Three Hours		15EC226E - SENSO (For the candidates admitted during)	B.Tech. DEGREE EXAM	Reg. No.	
12NF3-71/5EC226E	eration of sersor is called (B) Noise (D) Breakdown	An element that senses a variation in input energy to produce a variation in another or same form of energy is called (A) Electrode (B) Displacement (C) Sensor (D) Transducer	(D) Heat energy	tance transducer. (B) (I.VDT) linear variable differential transformer (D) Capacitive sensor	usducer can sense is known as (B) Resolution (D) Accuracy	(D) Mechanical energy to light energy	(B) Electrical energy to light energy	$ \begin{array}{c} (D) (\Delta R/R) \\ (\Delta L/L) \\ (D) (\Delta R/R) \\ (\Delta P/P) \end{array} $	PART - A (20 × 1 = 20 Marks) Answer ALL Questions	Max. Marks: 100	Part - A should be answered in OMR sheet within first 45 minutes and OMR sheet should be handed over to hall invigilator at the end of 45th minute. Part - B and Part - C should be answered in answer booklet.	15EC226E — SENSORS AND TRANSDUCERS (For the candidates admitted during the academic year 2015 – 2016 to 2017-2018)	B.Tech. DEGREE EXAMINATION, NOVEMBER 2018 3rd to 7th Semester		

displacement with a near magram		
b. Describe the working principle and construc	MEMS stands for (A) Micro electrical mechanical system (B) Micro electro mechanical system (C) Mini electro mechanical system (D) Mini electrical mechanical system	19.
30. a. Explain the circuit diagram and operation of c	(C) jun (D) cm	
 b. Explain magnetoresistive sensor based on t diagram. 	Resistor, capacitor conductors are example (A) $> 30 \times 10^{-3} m$	90
29. a. Describe the working principle and construction	(A) Light (C) Displacement (D) Temperature	7
b. Write about the classification of sensor		
(vi) Probable error	The detector used for x-ray and nuclear radiation (A) Pressure (B)	16.
	Gas sensing and enzyme substrate types are the two major subgroups under (A) Ion selective (B) Molecular selective (C) Metal electrode (D) Reference electrode	15
 a. The following values were obtained from the 147.2 Ω, 147.4 Ω, 147.9Ω, 148.1Ω, 147.1 Ω 147.5 Ω. Calculate 	The photovoltaic cell consists of a layer ofon metal disc. (A) Semiconductor (B) Insulator (C) Conductor (D) Non-metal	7
PART – C (5 × 12 = Answer ALL Q	Which material characteristics is very close to that of human eye? (A) Selenium (B) Cadmium (C) Silicon (D) Copper oxide	13. 4
	Which type of sensor used for detecting shaft position engine speed? (A) Temperature (B) Angle (C) Position (D) Magnetic	12. V
 Compare thin film and thick film sensor. Rrief about Mattencci effect and Villari effect. 	(A) Silicon (C) Rochele salt (D) Gallium assenide	30
Write short notes on synchros	Material used for niezpelectric sensor is	
 Write a note on eddy current sensor. 	The dielectric materials do not havepermittivity. (A) Infinite (B) Finite (C) Zero (D) Non-zero	10. 1
21 State the Hall effect sensor	Serrated plate capacitive sensors is used to measure (A) Change in inductance (B) Change in resistance (C) Change in capacitance (D) Change in impedance	,9 S C S
(A) PZT ceramic (C) POT	(A) Leakage current (B) Eddy current (C) Conventional current (D) Drift current	00

Sensors used for spin-dry system in washing machine is
 (A) PZT ceramic (B) Optical sensor
 (C) POT (D) Strain gauge

 $5 \times 4 = 20$ Marks) Y FIVE Questions

of sensor with diagram.

5 x 12 = 60 Marks) ALL Questions

from the measurements of the value of a resistor: 147.1 Ω , 147.5 Ω , 147.6 Ω , 147.4 Ω , 147.6 Ω and

struction of different types of strain gauge.

(OR)
ed on the principle and their types with a suitable

on of capacitive proximity sensor.

onstruction of LVDT and how it is used to measure

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